Inventor(s): Ke Serial No.: To Be Assigned Filed: Herewith

For: Reducing Photoresist Shrinkage Via Plasma Treatment Attorney Docket No.: 67,200-641

1/3

FIG 1A

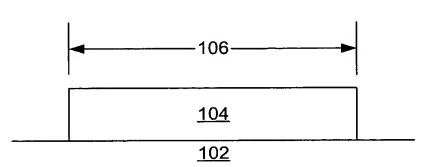


FIG 1B

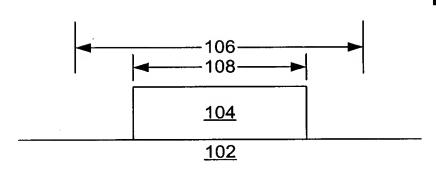
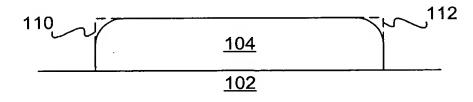


FIG 1C



304b

302b

_<302a

300

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FIG 2

FIG 3

306b

Inventor(s): Ke Serial No.: To Be Assigned Filed: Herewith Reducing Photoresist Shrinkage Via Plasma Treatment Attorney Docket No.: 67,200-641 3/3 PLASMA 408 402 410 404 414 SUBSTRATE MASK POLY